

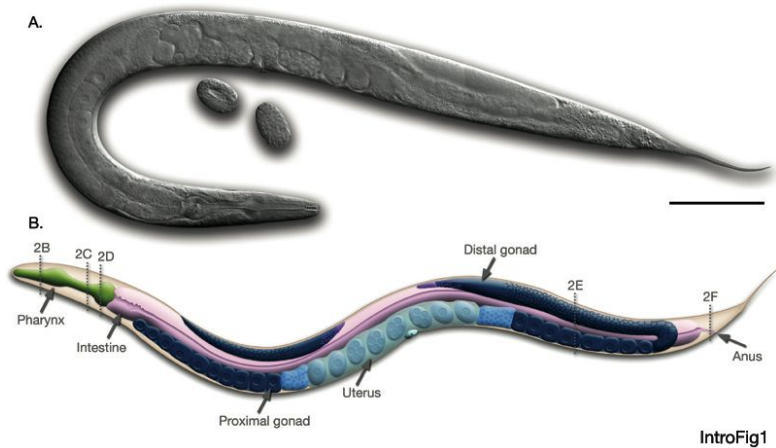
Research Update

Joey Doll
Worm Club
10/1/2009

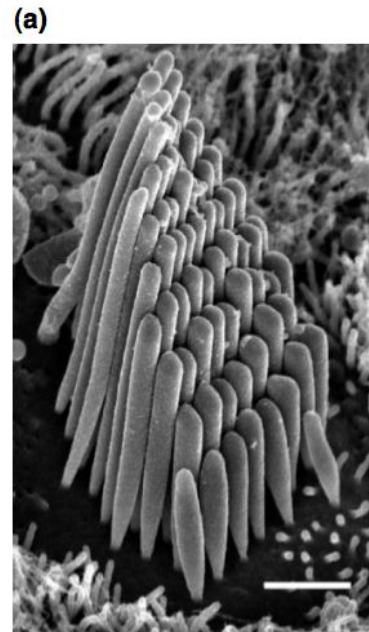
Today

- Feedback modeling
- Circuit design
- Printed circuit boards
- PR+PE Characterization

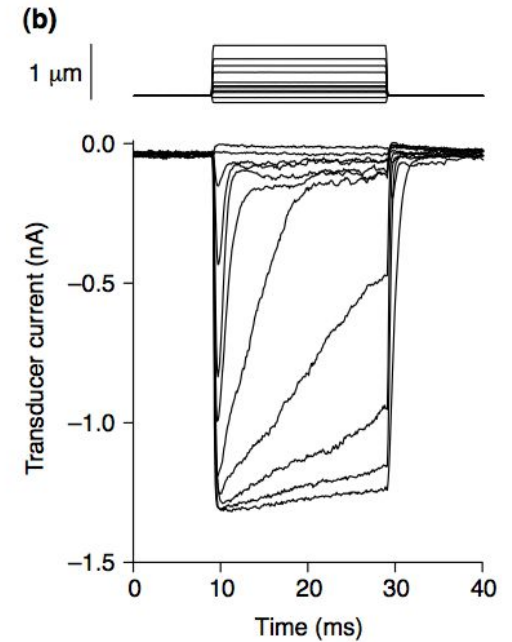
Motivation



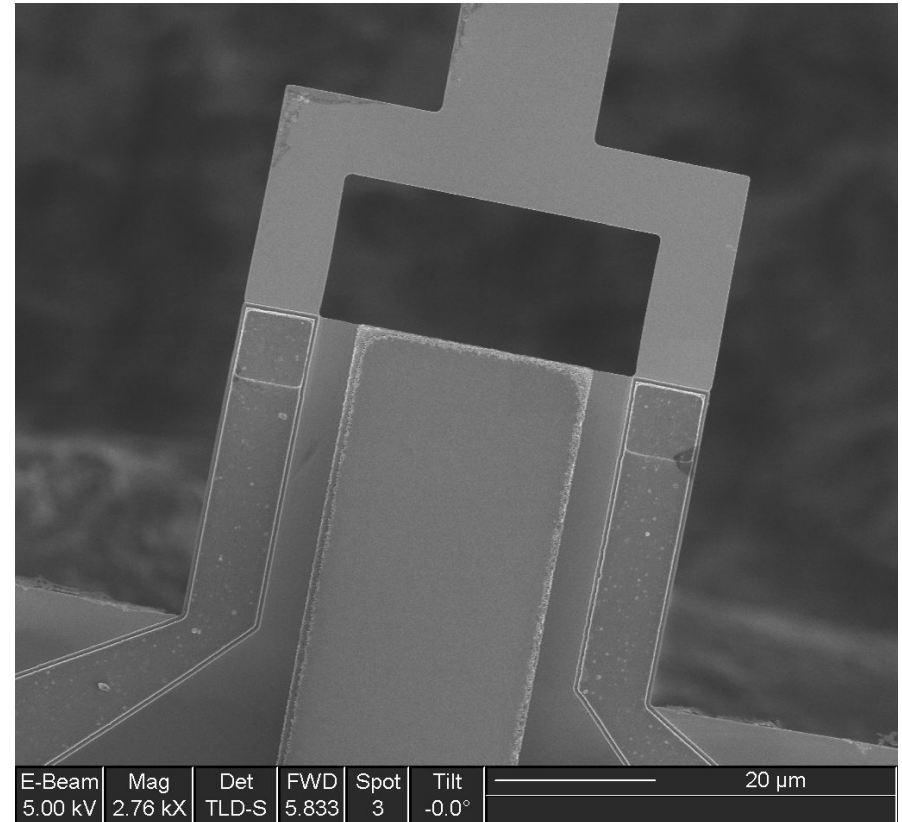
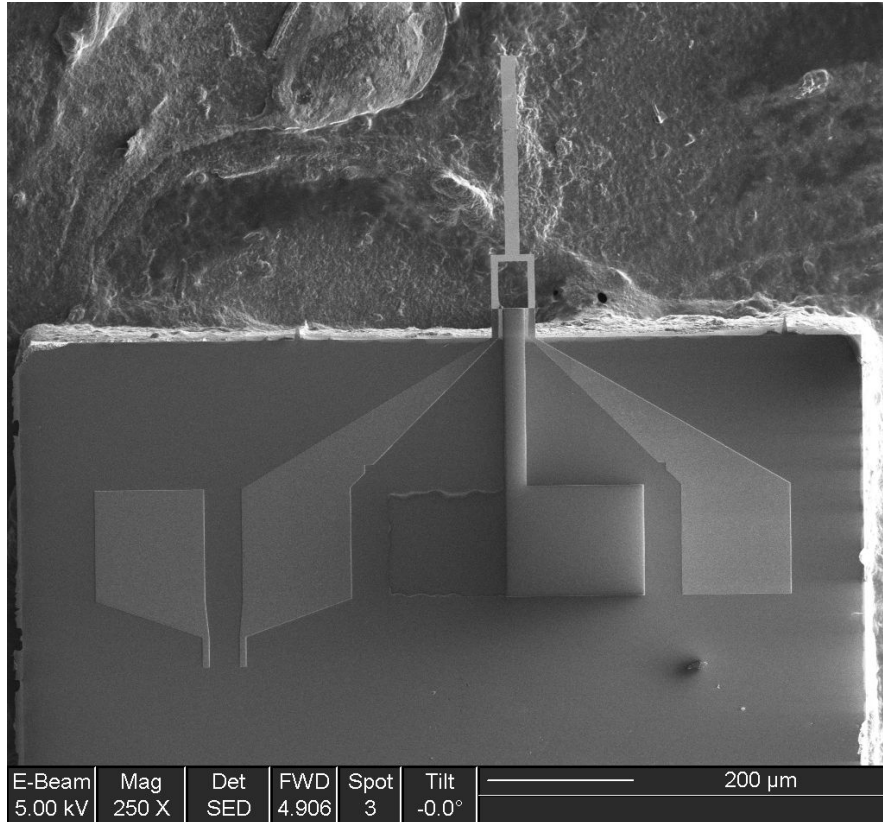
Worm TRNs



Turtle hair cell

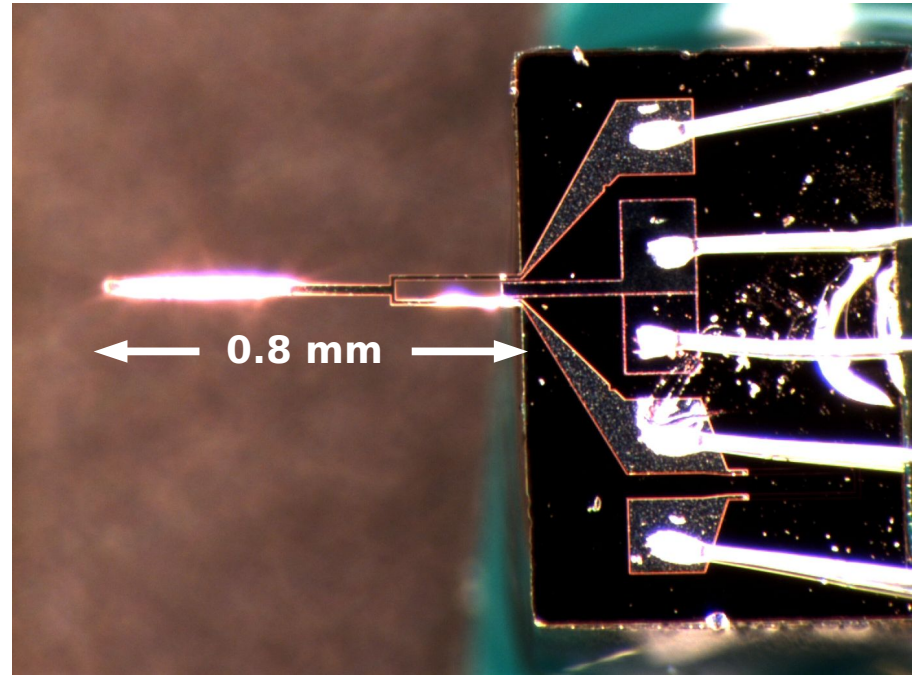
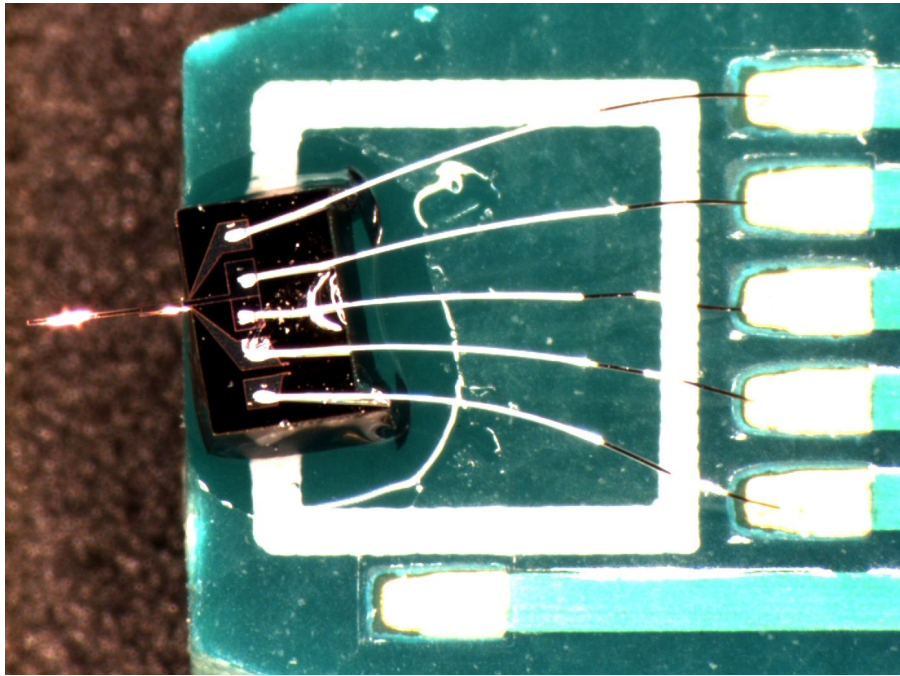


The Device

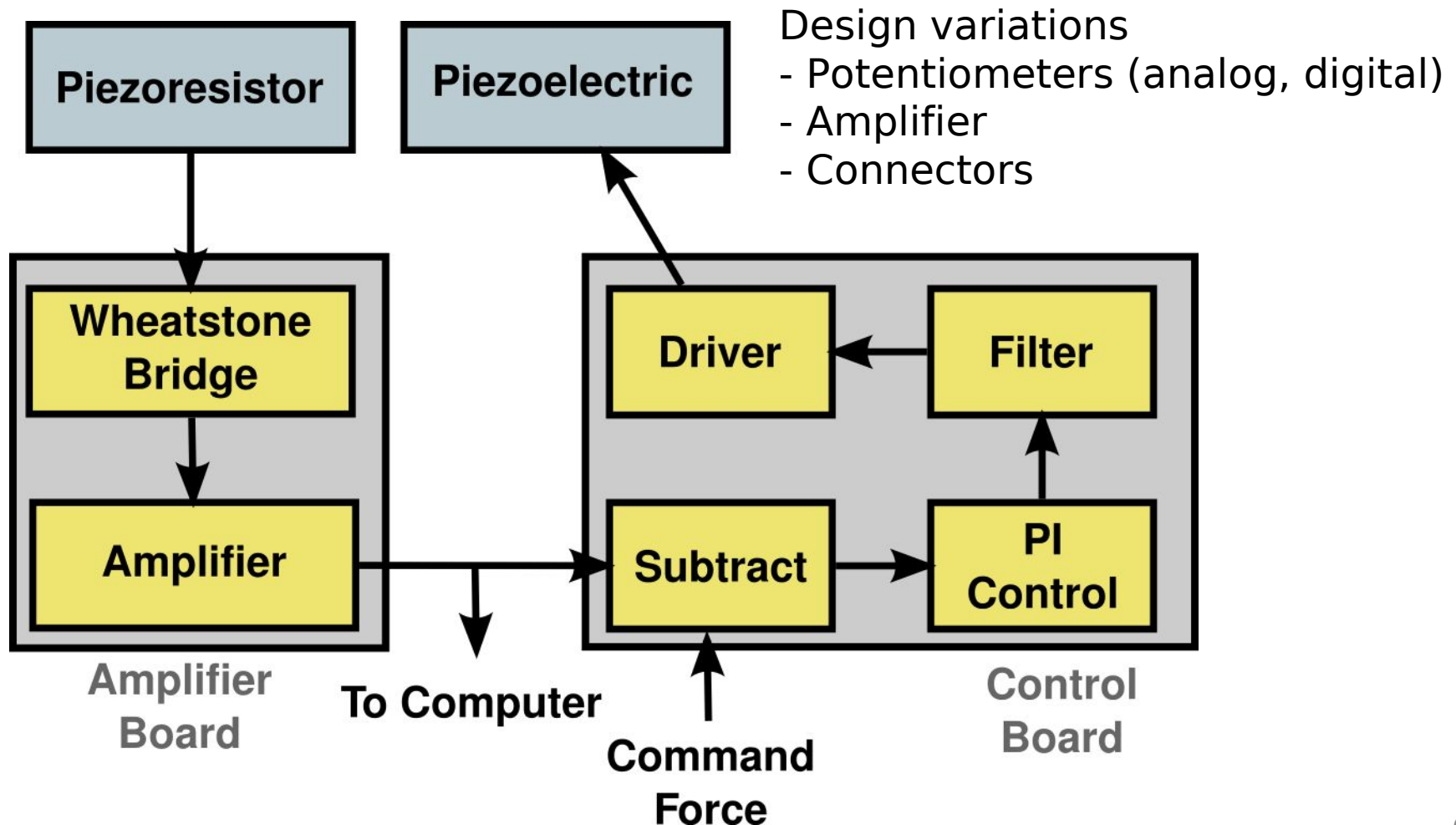


Piezoresistive force detection
Piezoelectric actuation

The Device

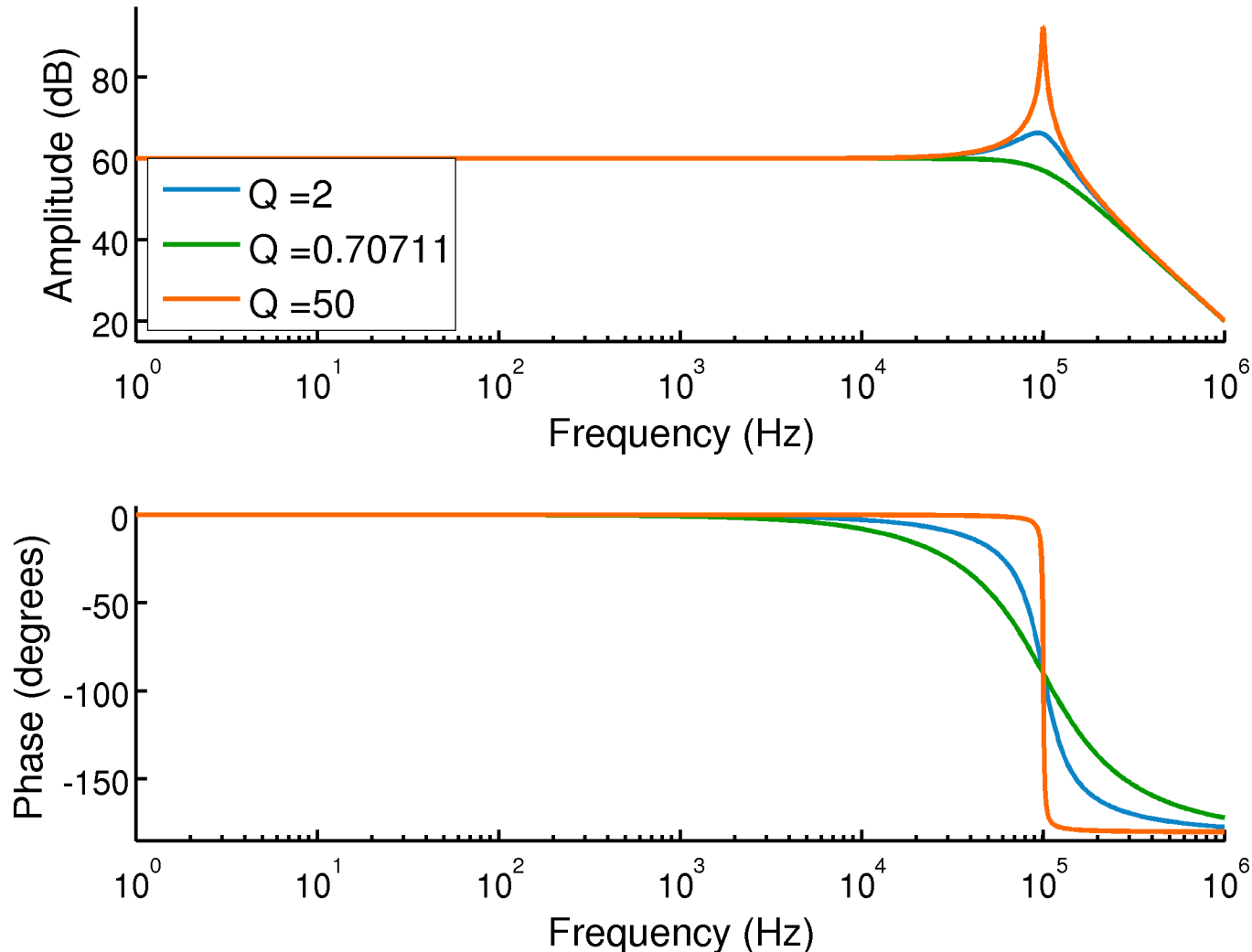


Circuit/Control Overview

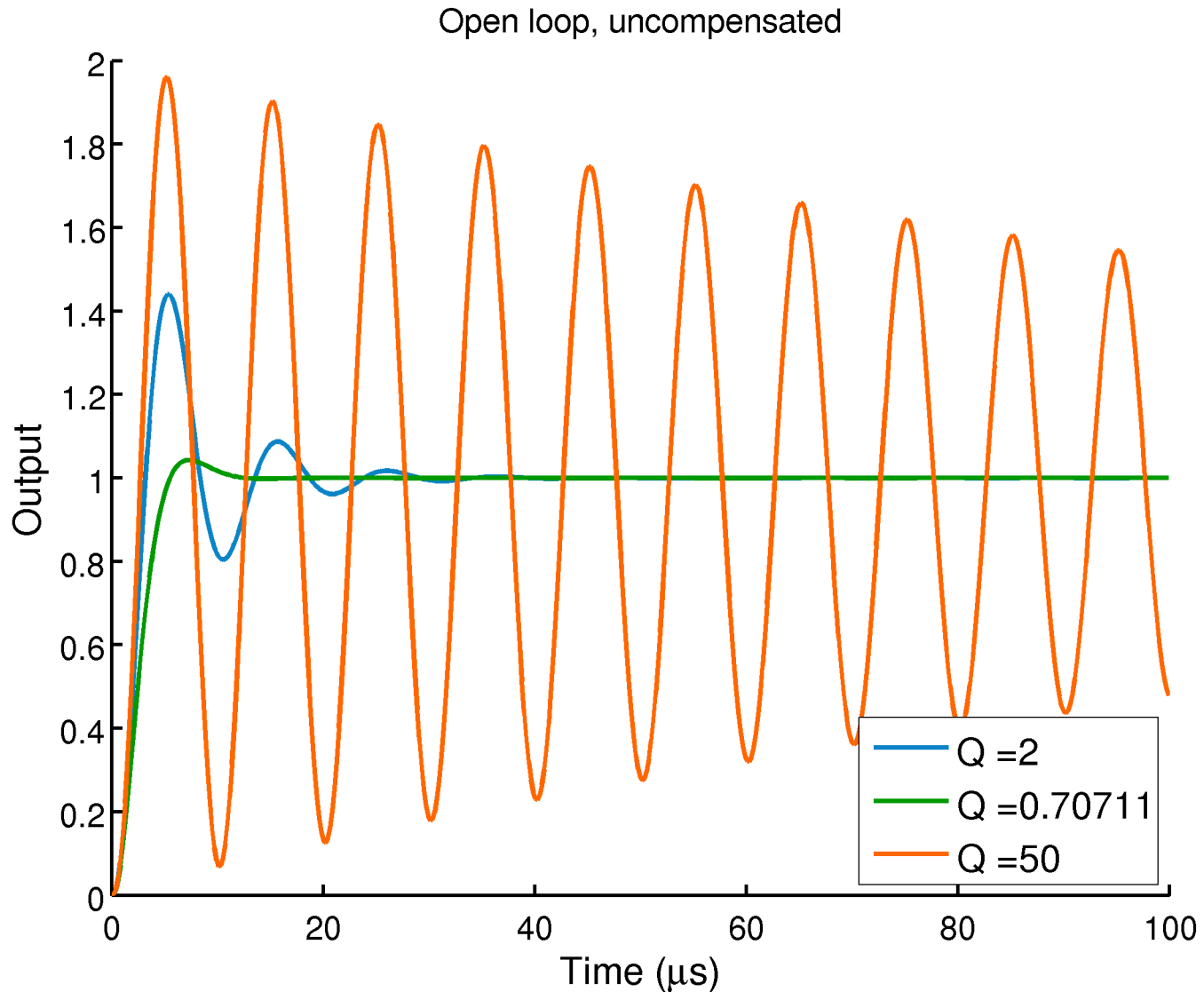


Feedback Modeling

Uncompensated cantilever open loop response

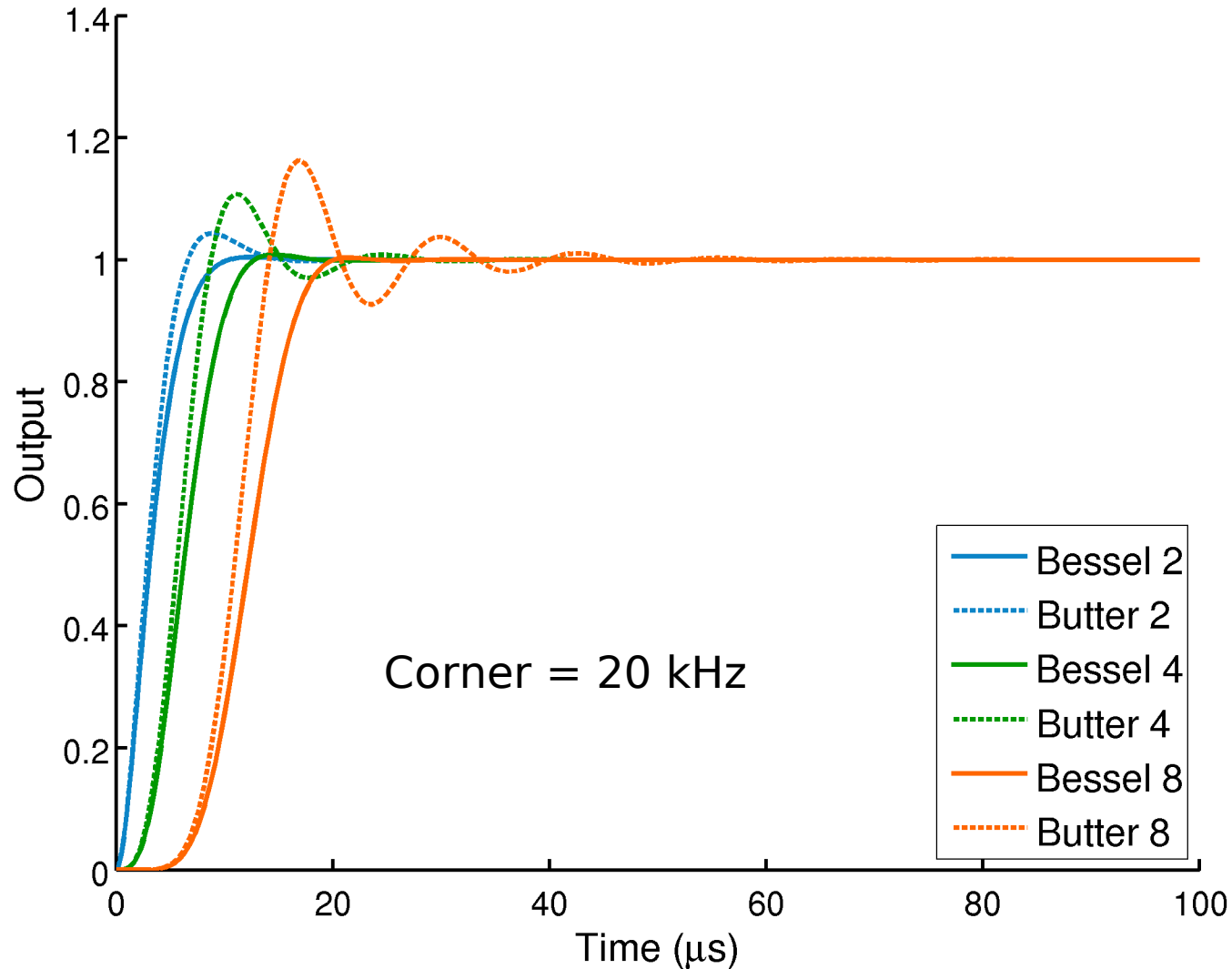


Feedback Modeling



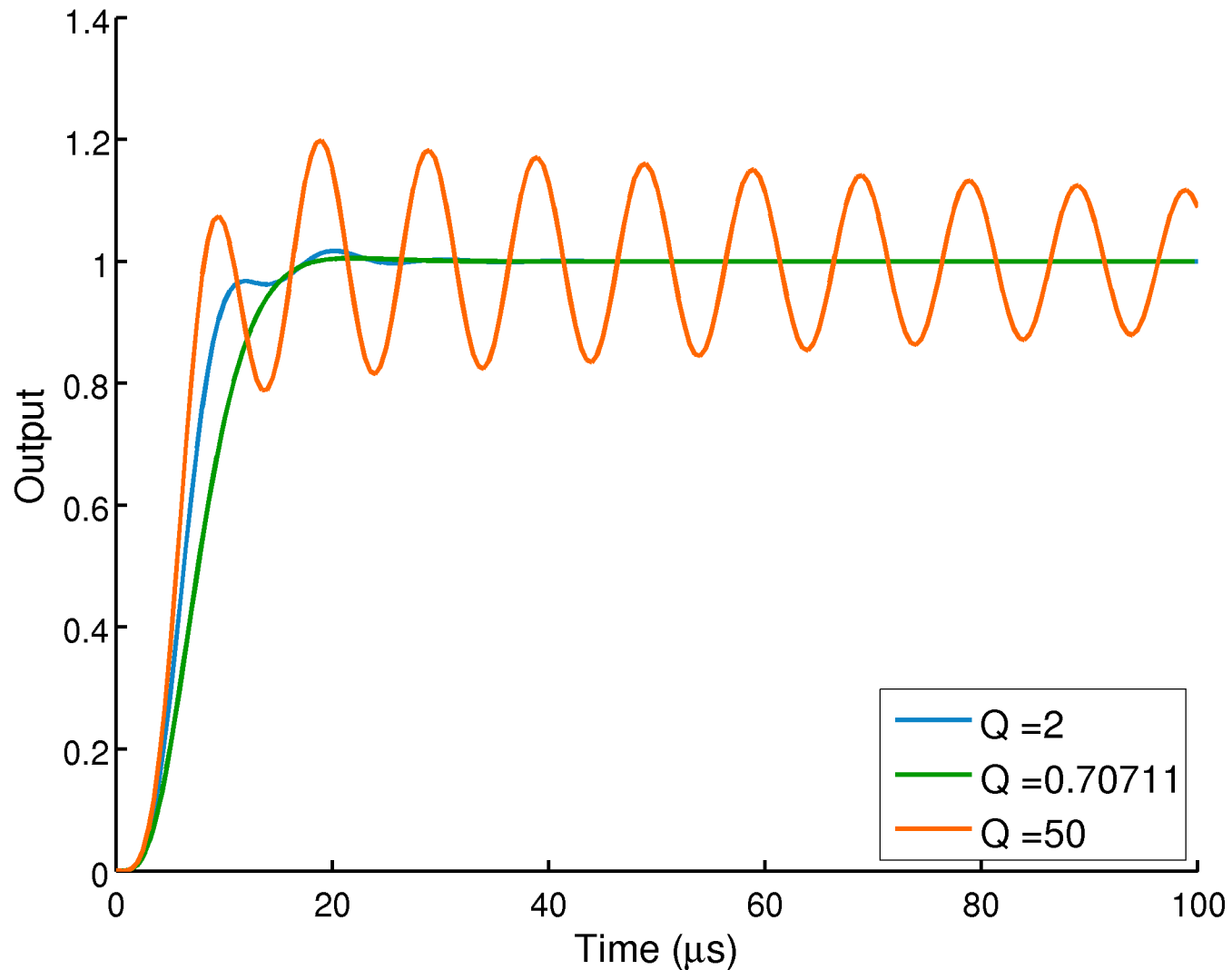
Feedback Modeling

Step response of bessel and butterworth filters



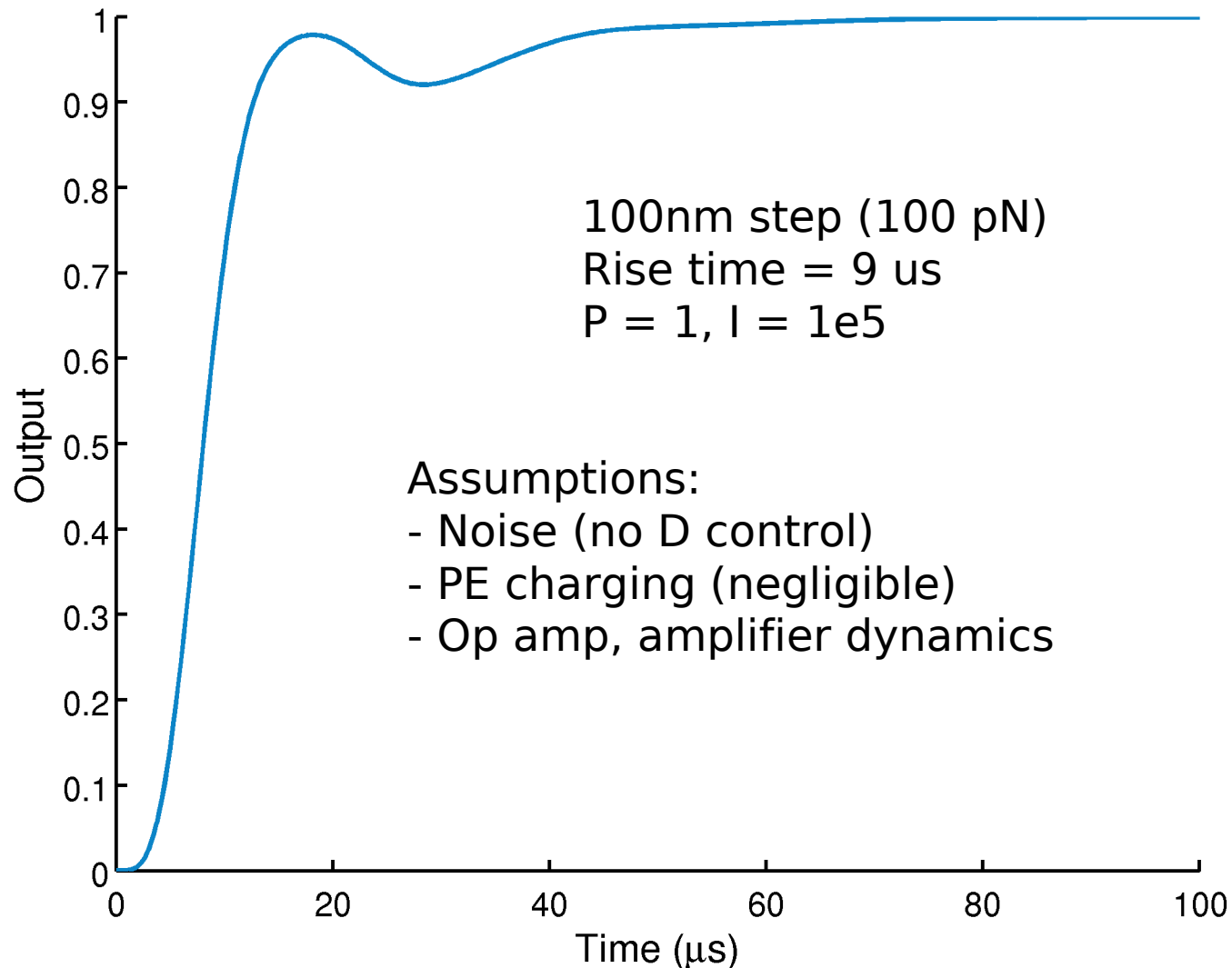
Feedback Modeling

Open loop, 2nd order low pass on output

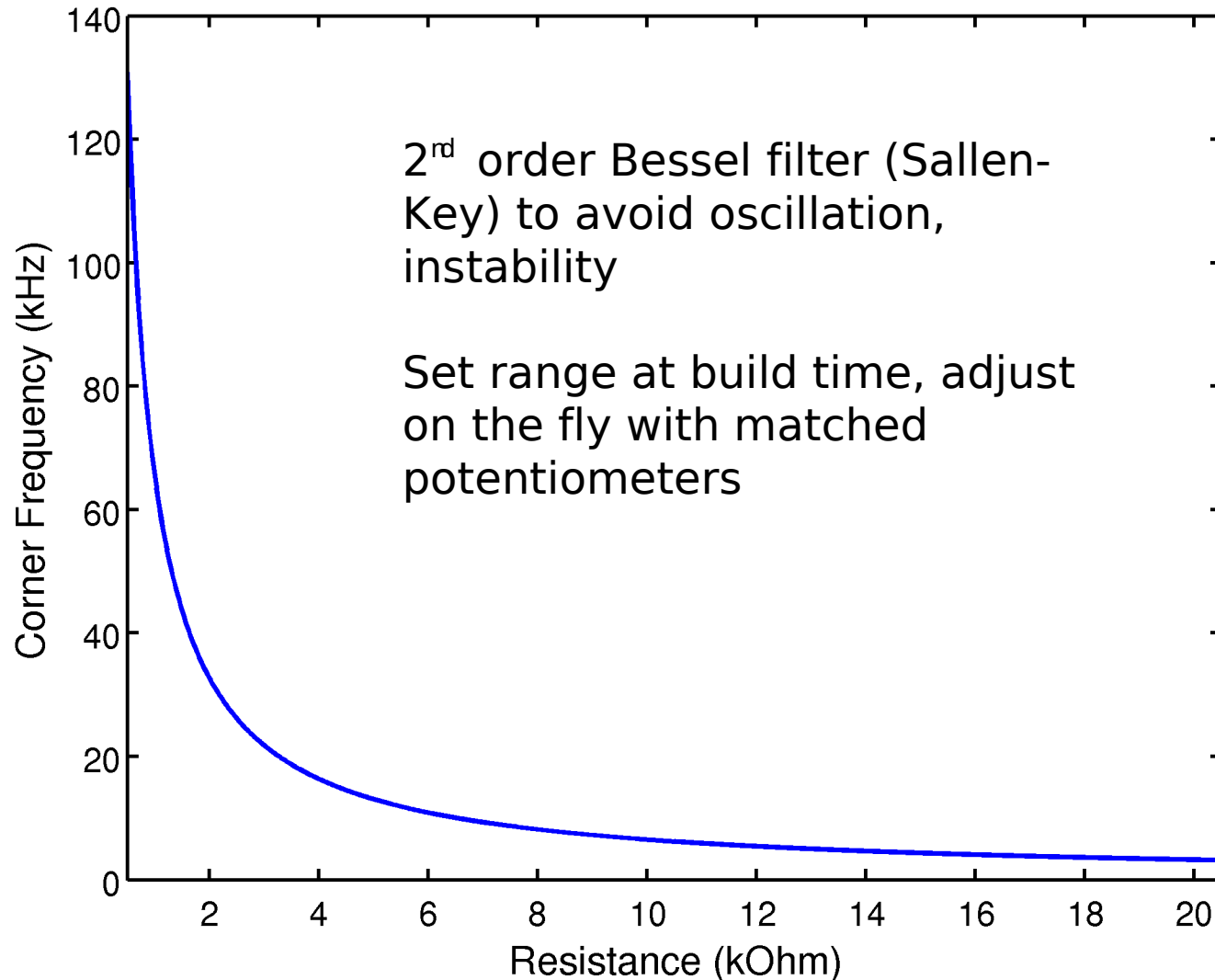


Feedback Modeling

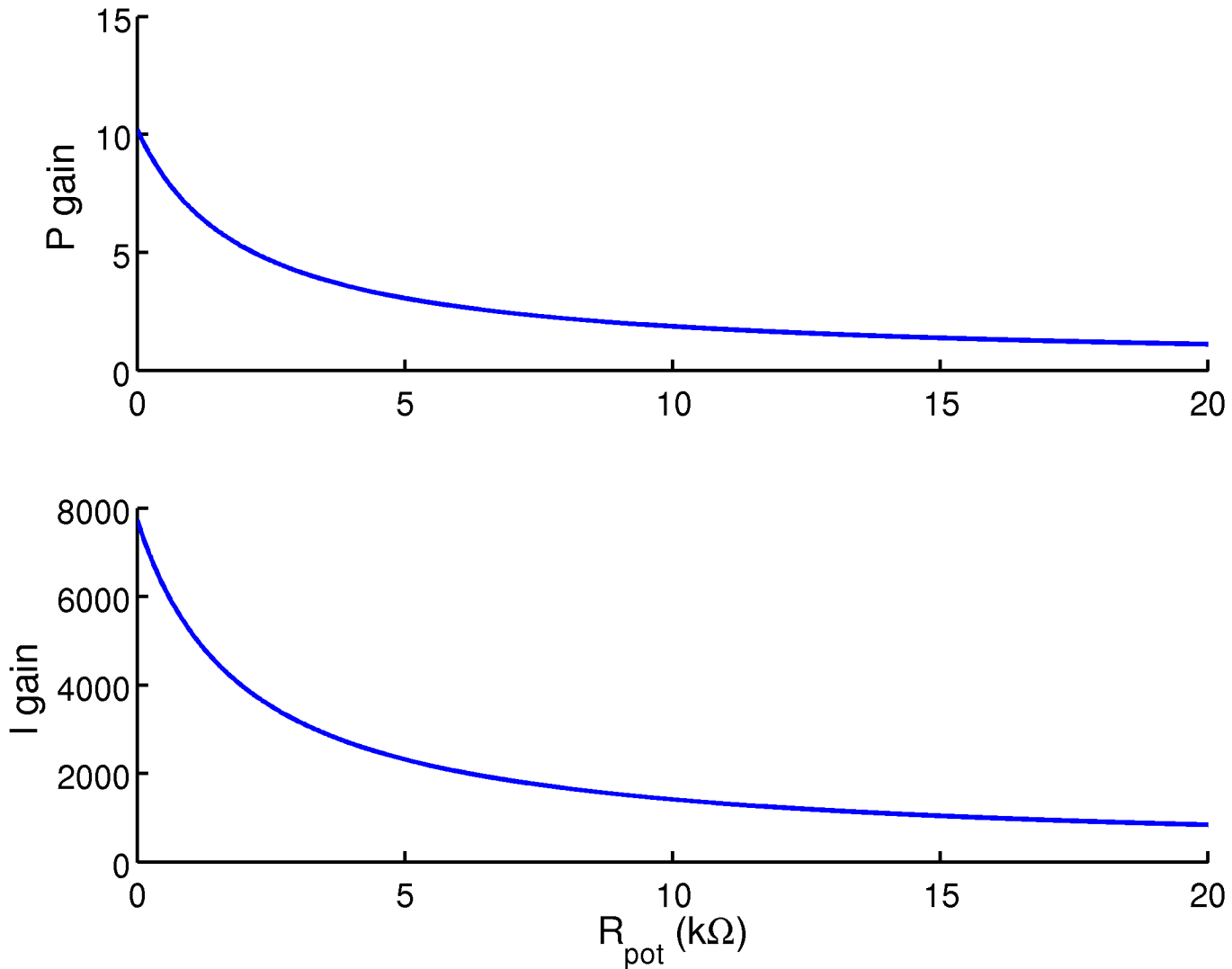
Closed loop, PID compensated, 2nd order Bessel, medium Q, lever = 100kHz, LP = 30kHz



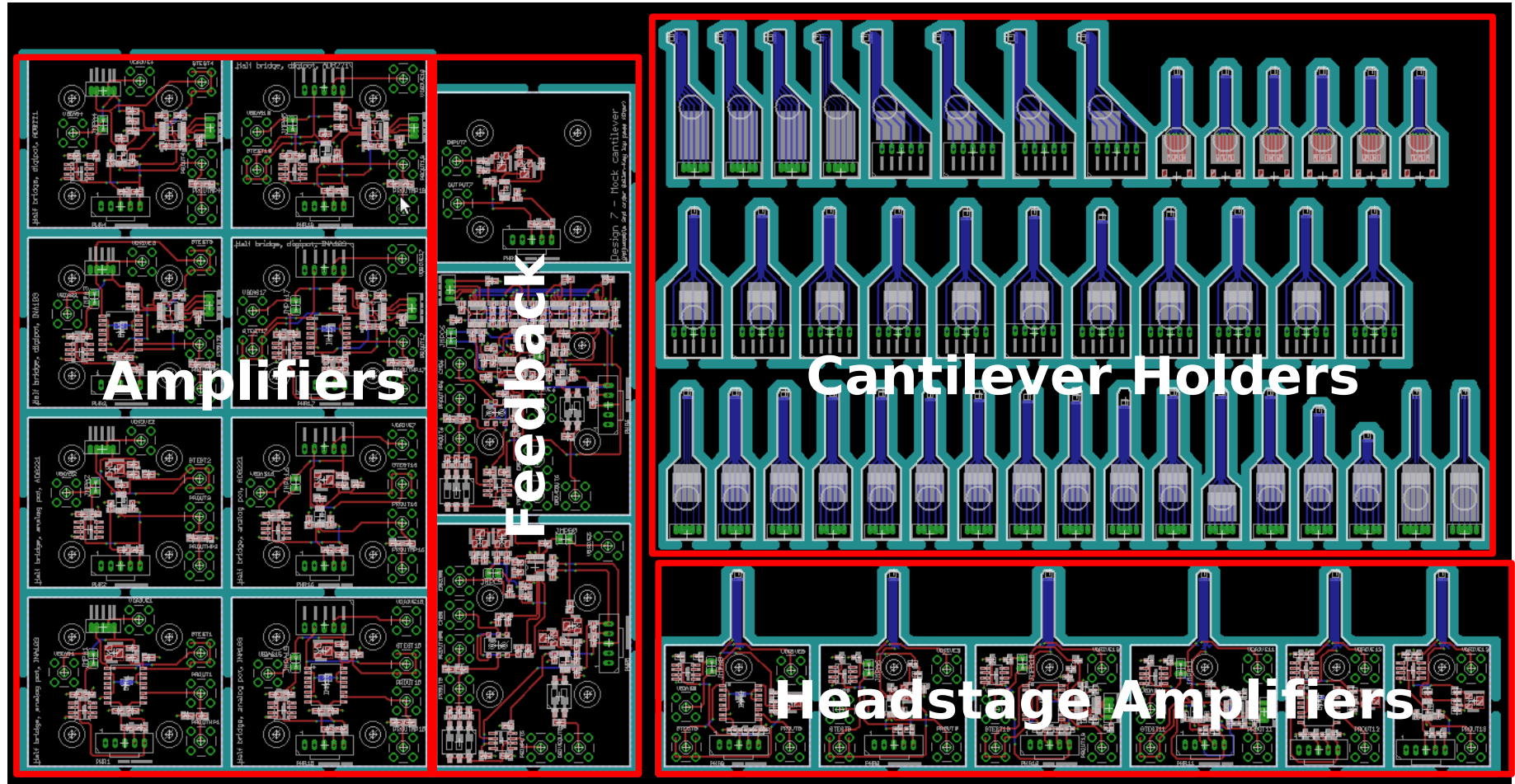
Circuit Design



Circuit Design

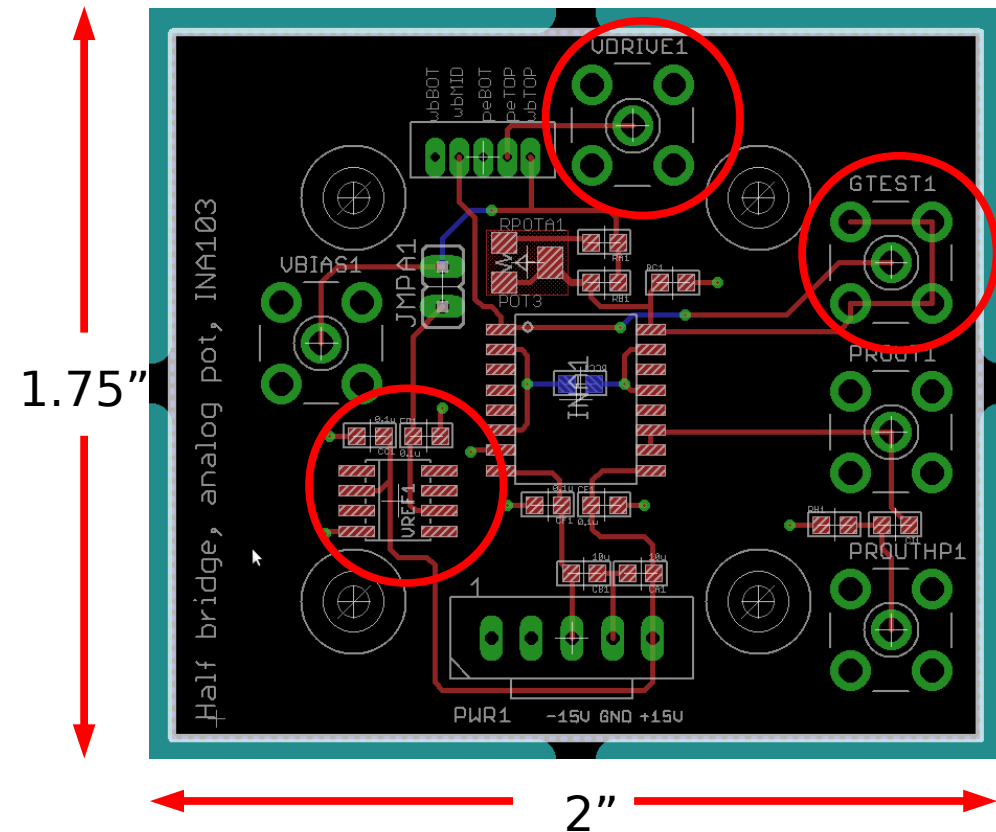


PCB Layout

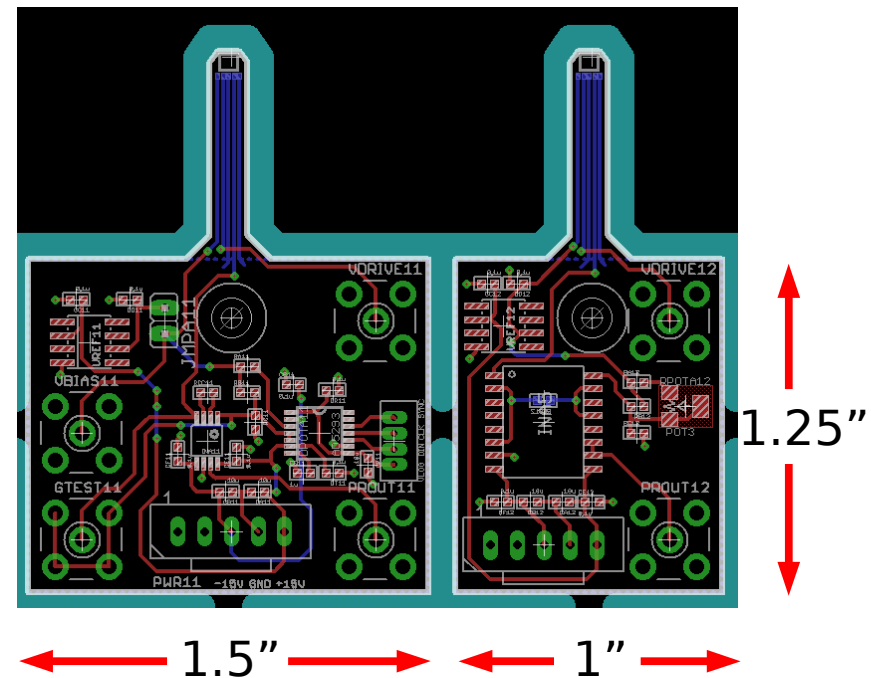


Ordered, received, mostly assembled and tested

Circuits - Amplifiers

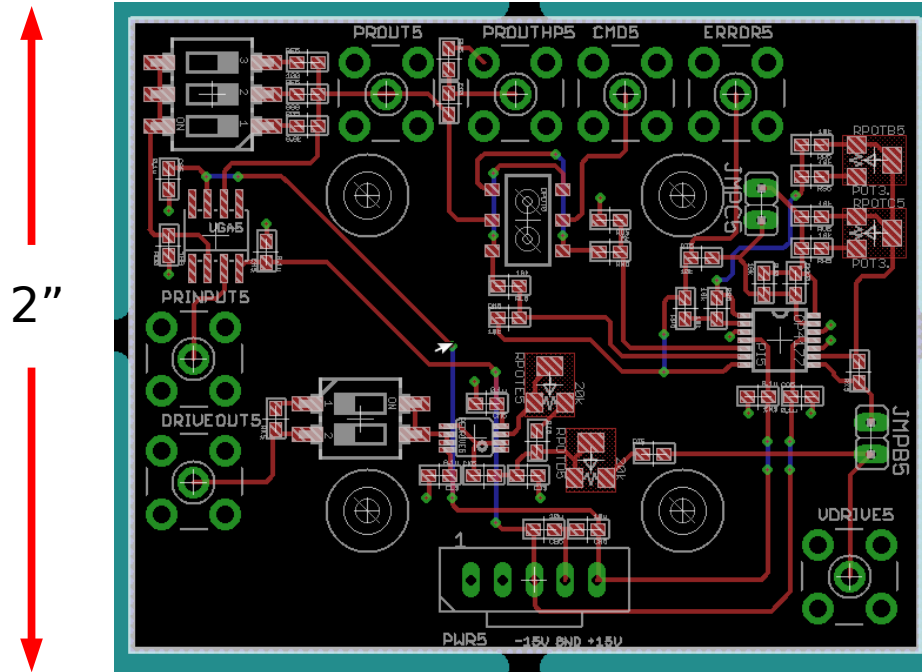


Skinnier tips this time



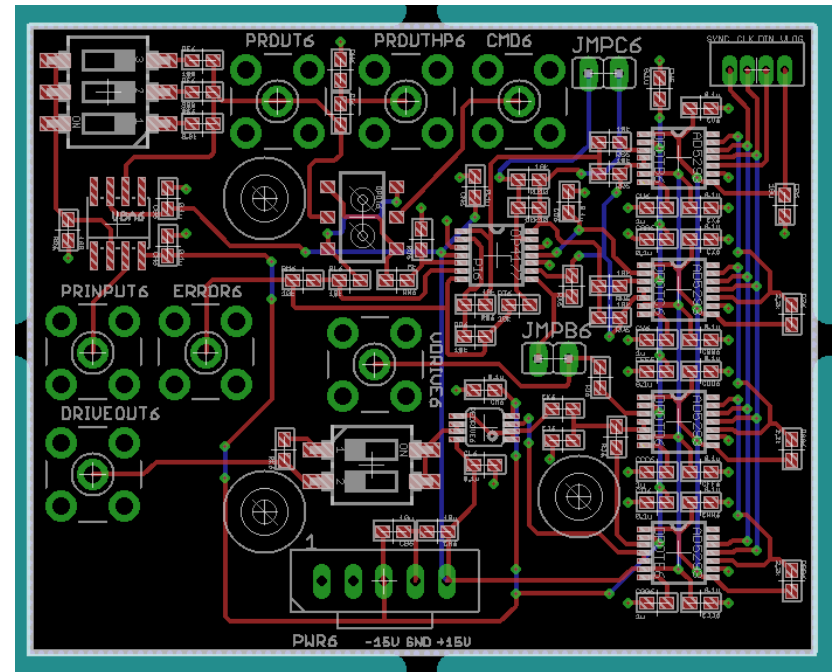
Circuits - Feedback

Analog Potentiometers



2.5"

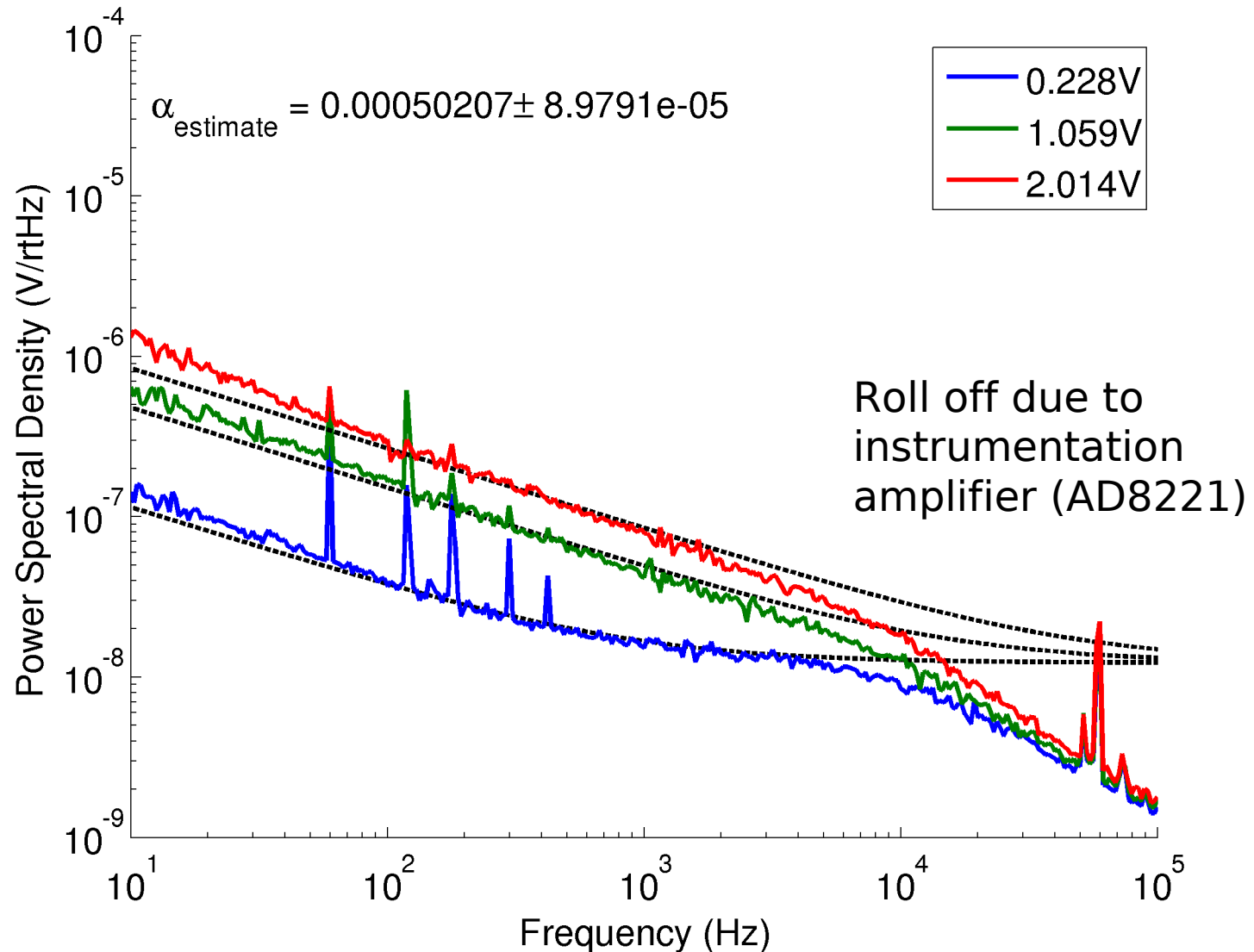
Digital Potentiometers



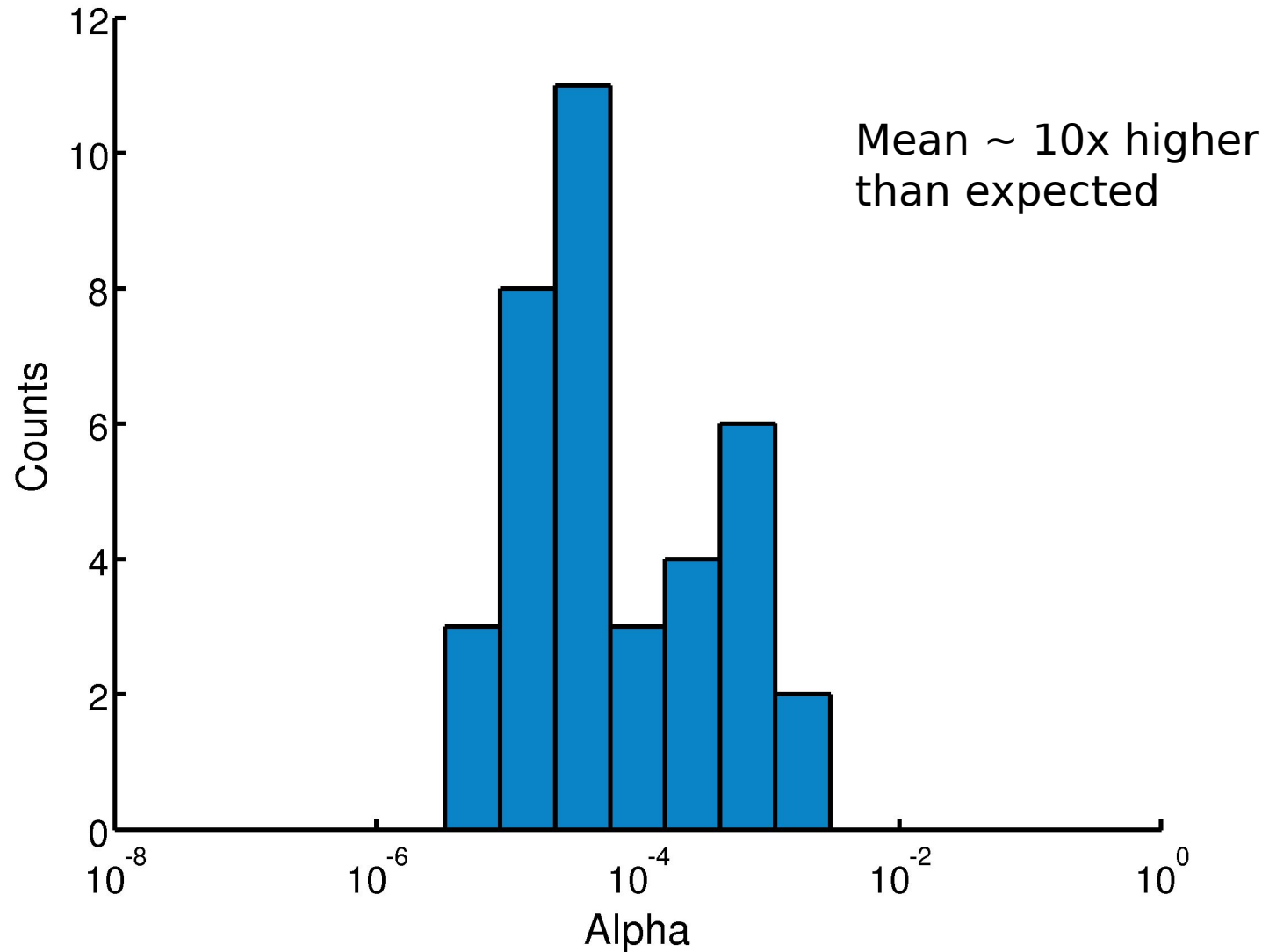
Device Characterization

- **Noise spectrum**
- **Piezoresistor resistance**
- **Spring constant**
- **Electrical cross-talk**
- Force/displacement sensitivity
- Actuation distance

Noise spectra look good



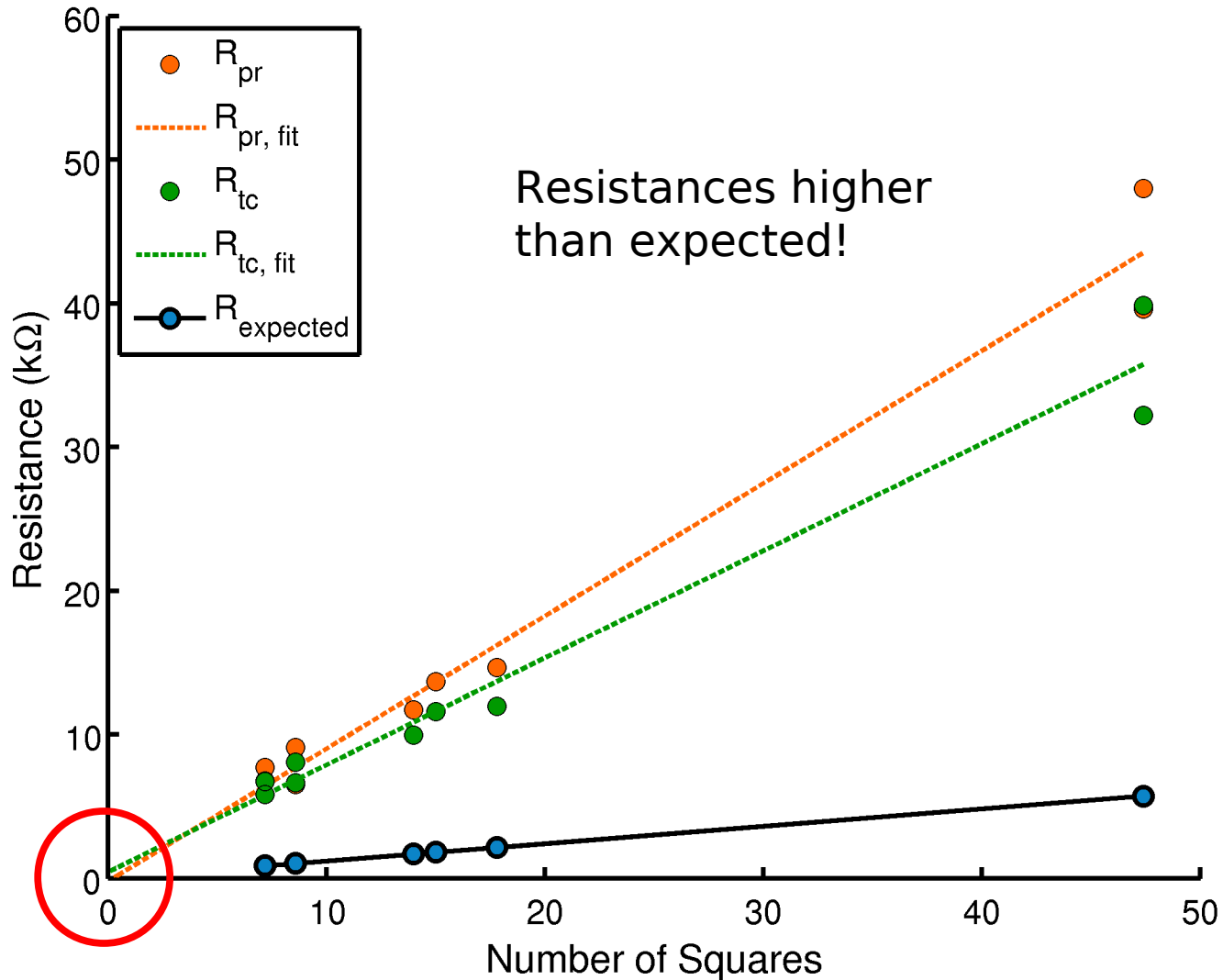
1/f noise higher than expected



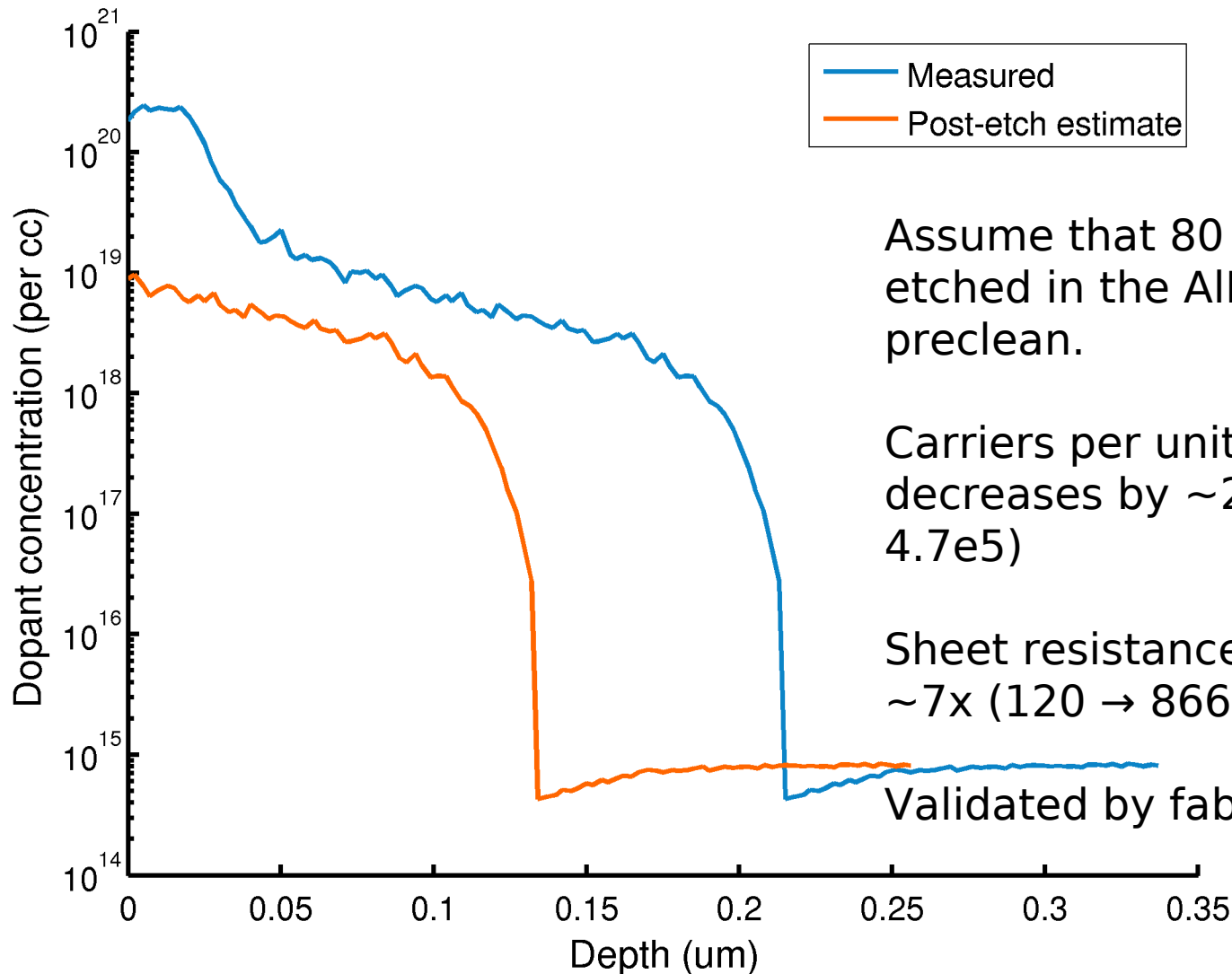
Two unknowns, one equation

- Alpha is higher than expected or Nz is lower than expected. Which?
- Need an additional parameter for fitting.

Piezoresistor resistance



Accidental etching



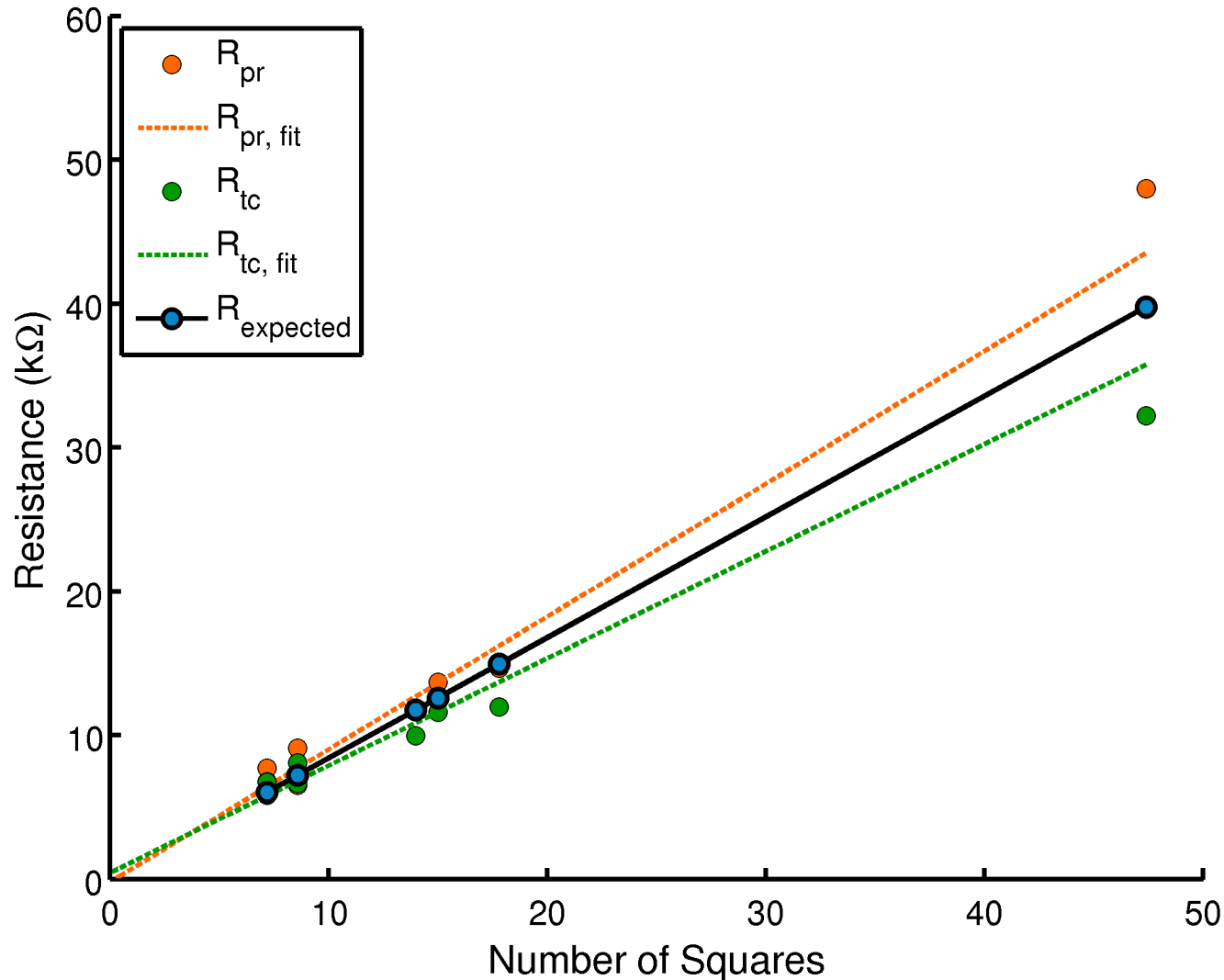
Assume that 80 nm of Si was etched in the AlN deposition preclean.

Carriers per unit depth decreases by $\sim 20\times$ ($7e6 \rightarrow 4.7e5$)

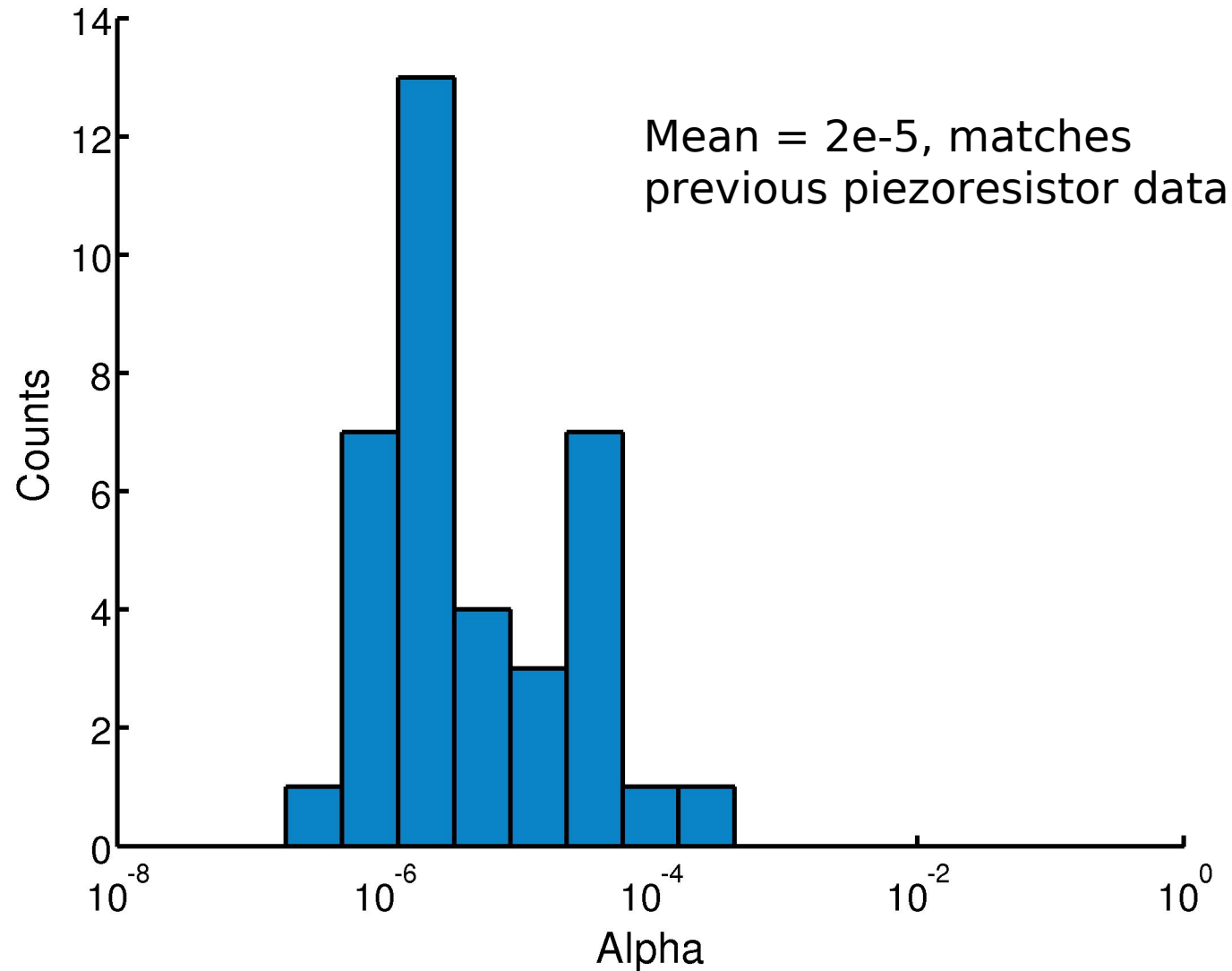
Sheet resistance increases by $\sim 7\times$ ($120 \rightarrow 866$ ohms/sq)

Validated by fab measurements

Adjusted resistance model



Alpha adjustment



Overall impact?

- Noise is higher
 - Johnson noise $\sim 2.5x$ higher
 - $1/f$ noise $\sim 10x$ higher
- Sensitivity is higher
 - Beta^* $\sim 2x$ higher
 - Thickness $\sim 50\%$ less
- Net effect = $5x$ worse force resolution
 - Back of the envelope, will vary...

Spring Constant

- Can estimate spring constant from resonant frequency, cantilever geometry
 - Complicated geometry, made some assumptions for now, FEA later
- Measured thermomechanical noise spectrum using LDV

Spring Constant

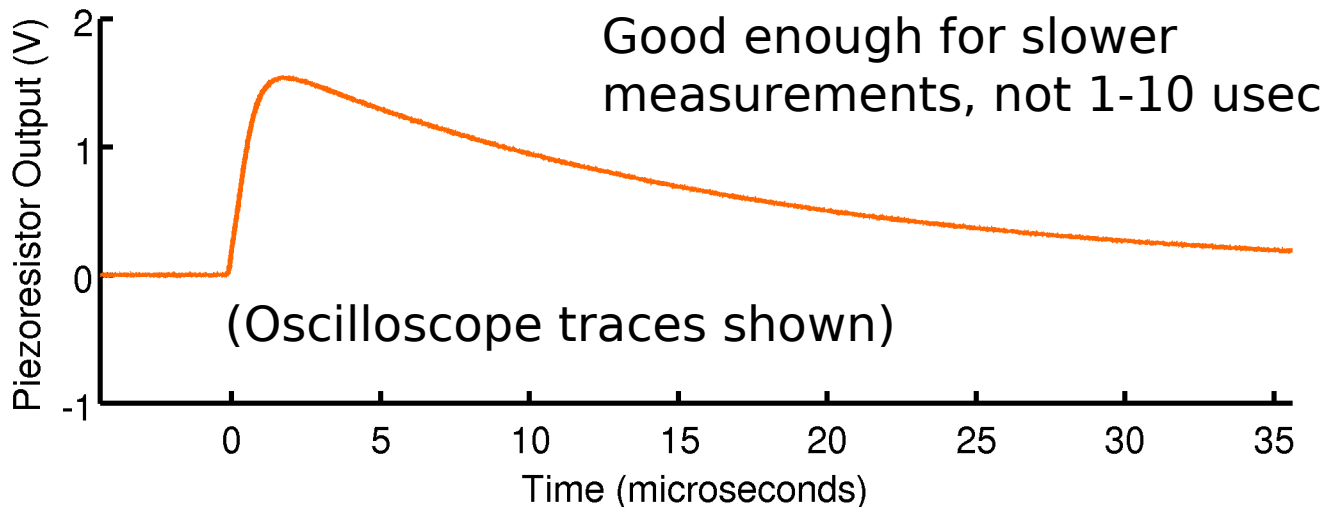
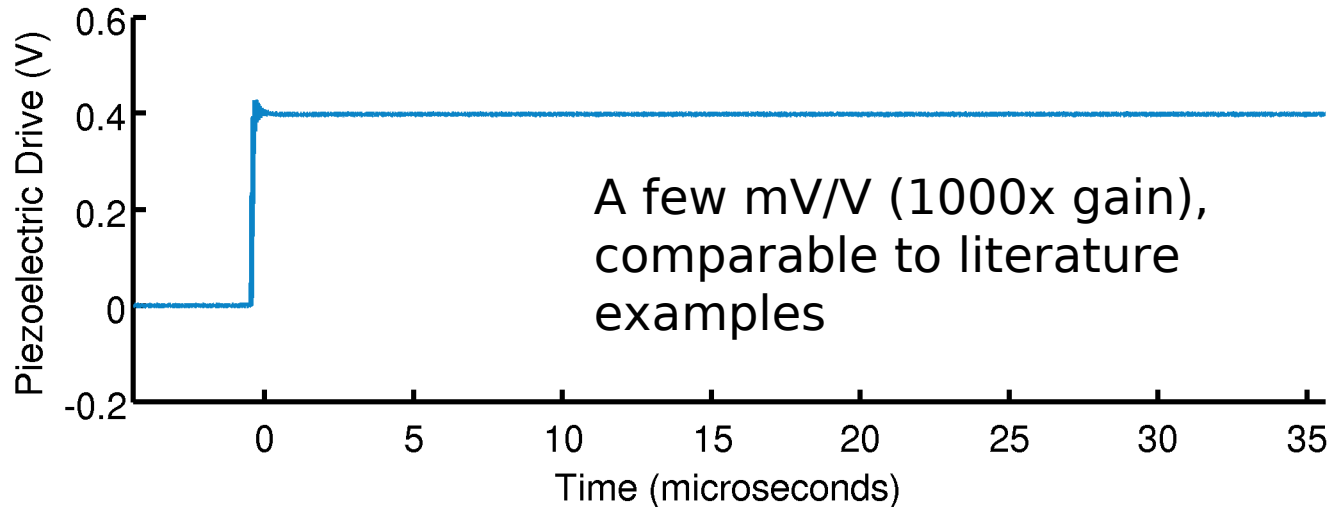
Design #	Theoretical Frequency (kHz)	Measured Frequency (kHz)	Estimated Stiffness (pN/nm)
1	0.5	0.5	2.0
2	2.1	1.8	0.02
3	10.7	13.2	0.1
4	84.8	128.9	3
5	0.9	1.2	100
6	4	8.25	0.09

Ballpark estimates. $N=1$ for each, simplified model.

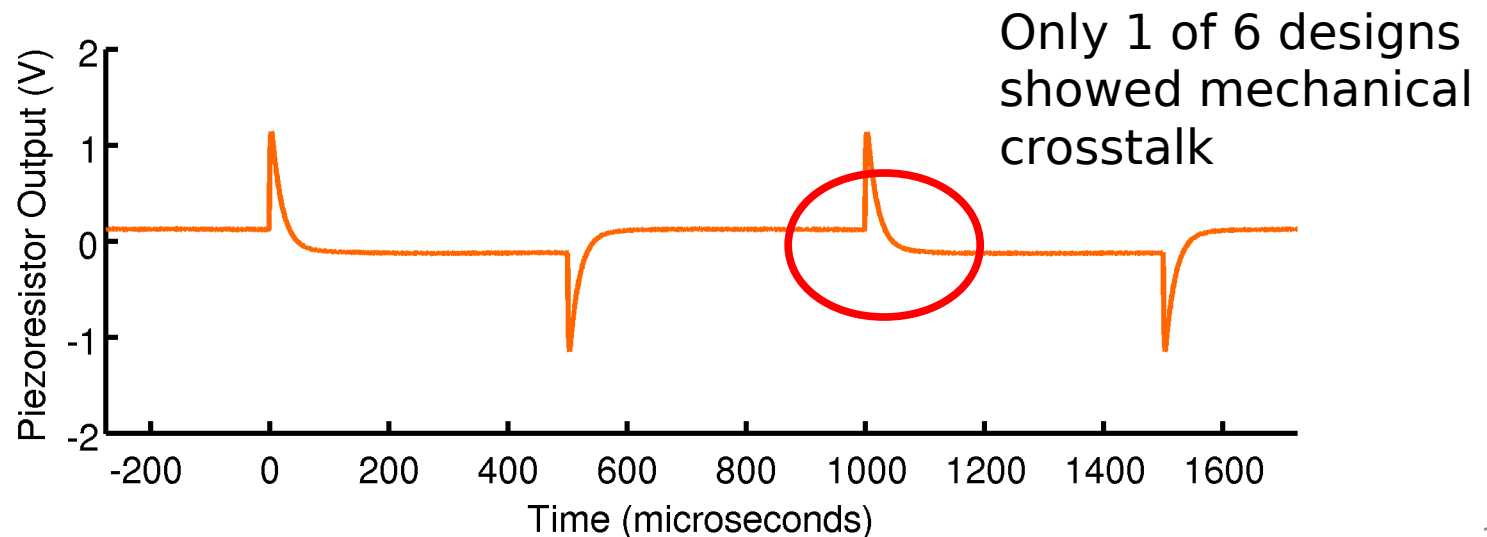
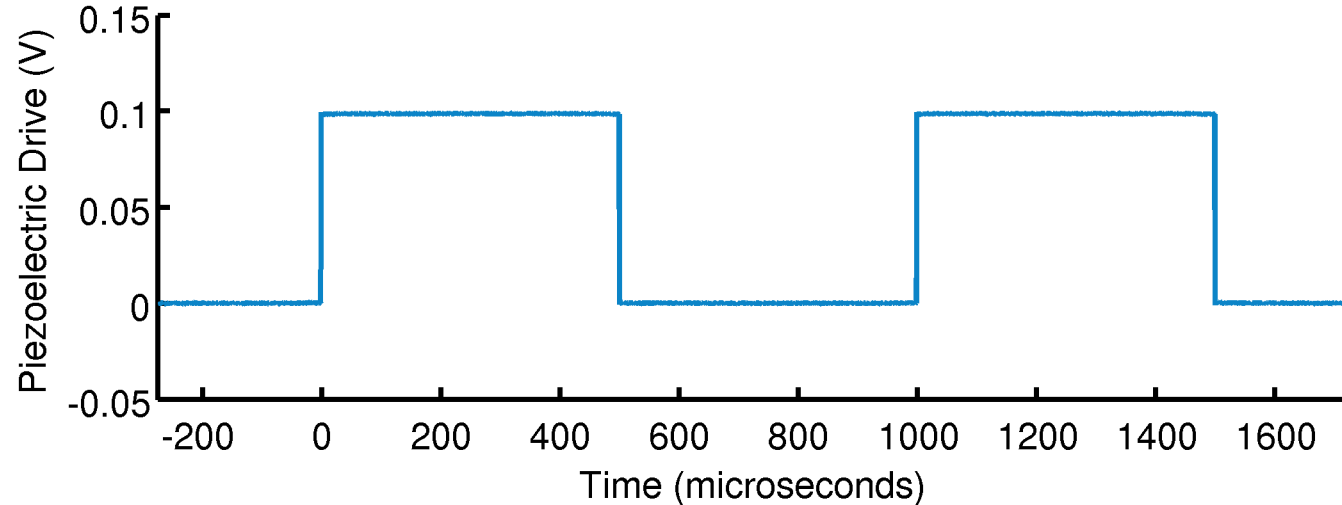
Crosstalk overview

- Showed preliminary data last time, but not a realistic experimental setup
- This time: using actual PCB, cables, etc. that would be used for experiments
- Possible mechanisms
 - Capacitive: worse at higher frequencies, due to changing voltages in vicinity of each other
 - Mechanical: Piezoelectric bending changes piezoresistor resistance

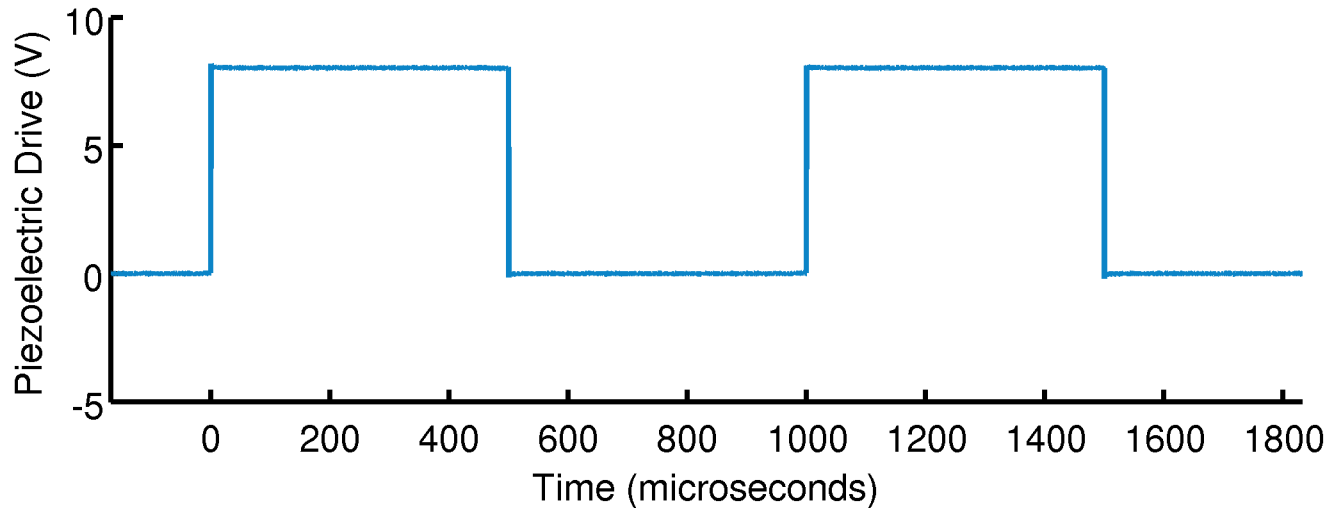
There is capacitive crosstalk



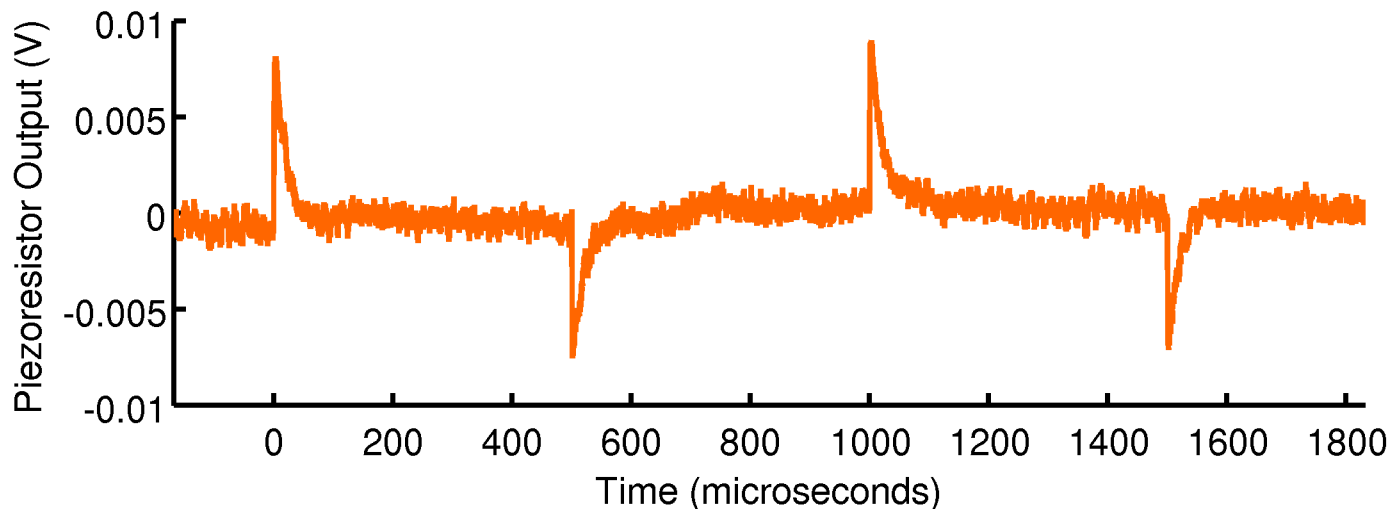
Some mechanical crosstalk



Minimal crosstalk from PCB

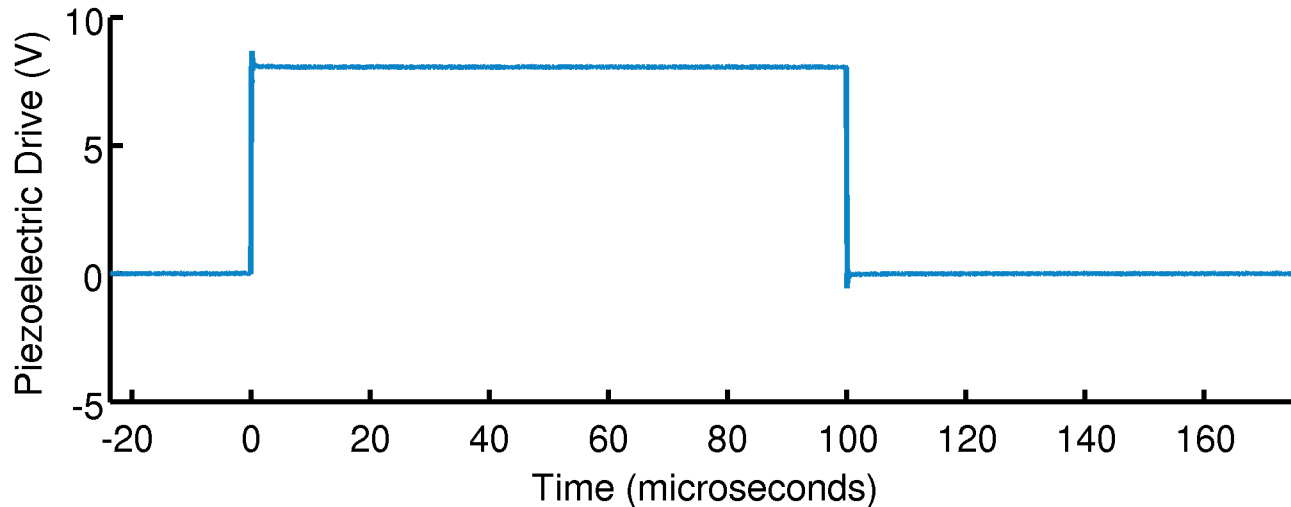


Connected
discrete resistors
and capacitors in
place of the
cantilever

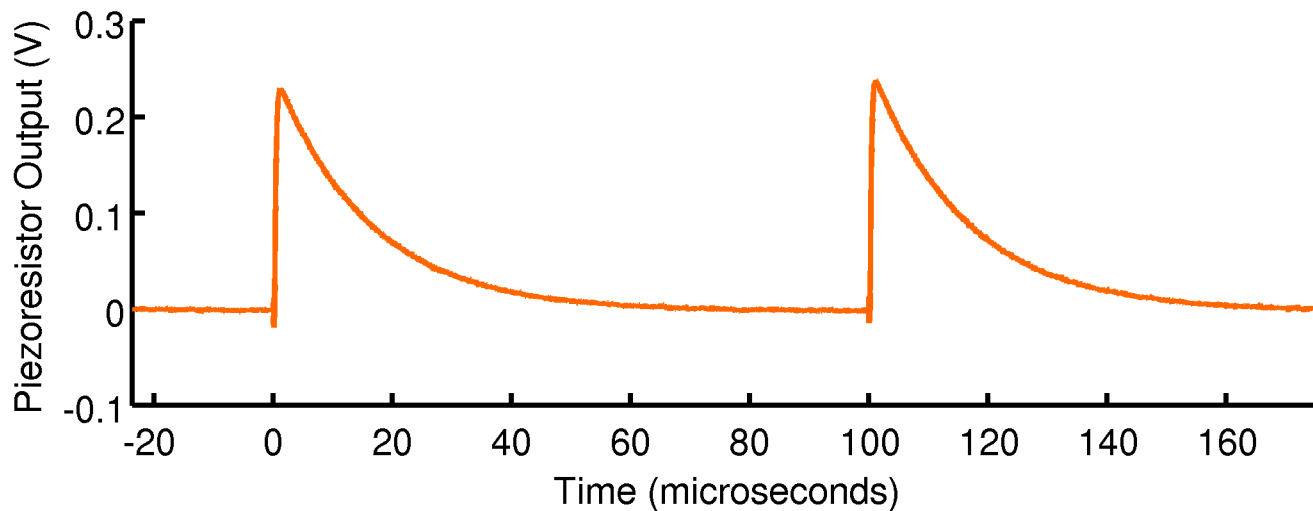


Also no crosstalk
from the cable
(shielded)

Some crosstalk from cantilever PCB



Connected cantilever PCB, shorted the bondpads by wirebonding



Crosstalk – What next?

- Investigate with more devices, measurement conditions
- Model in terms of device design parameters
- Affects highest speed measurements, not bad enough to stop system development, slower demonstration measurements (msec)
- Solution: compensation on silicon die (next fab run) – piezoelectric next to temperature compensation PR

Conclusions

- Piezoresistors are noisier, higher resistance than expected, but minimal impact on performance.
- There is electrical crosstalk on the microsecond scale.
- Devices usable for system testing and some measurements.

What's next?

- Test feedback control (mock cantilever)
- Measure PR force sensitivity, tip deflection
- Demonstrate on microscope in MERL
- Choose an experiment based upon performance
- Fab run for improved devices